



PATENT ABSTRACTS OF JAPAN

(11) Publication number: 2001156055 A

(43) Date of publication of application: 08.06.2001

(51) Int. Cl. H01L 21/31

B05B 7/04, C23C 16/448, F17C 7/00, H01L 21/205

(21) Application number: 2000225445

(22) Date of filing: 26.07.2000

(30) Priority: 14.09.1999 JP 11260819

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(54) METHOD AND APPARATUS FOR GASIFYING LIQUID MATERIAL

(57) Abstract:

PROBLEM TO BE SOLVED: To provide a method and an apparatus for gasifying a liquid material whereby the liquid material can be gasified always with good efficiency and stably.

SOLUTION: The liquid material LM and a carrier gas CG are mixed under the flow rate control in a gas-liquid mixing part 39 inside a control valve 1 having a liquid flow rate control function, and resultant gas-liquid mixture M is discharged from a nozzle 42 formed near the flow rate controller 39 to reduce the pressure and gasify the liquid material LM.

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